

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application

Inventor(s): Tue Nguyen, Tai Dung Nguyen

Appln. No.: 09/898,439

Appeal No.: 2009-1022

Conf. No.: 1885

Filed: July 5, 2001

Title: PLASMA SEMICONDUCTOR
PROCESSING SYSTEM AND METHOD

PATENT APPLICATION

Art Unit: 2892

Examiner: Quoc Dinh Hoang

Atty. Docket No.: TEGL-01165US0

Customer No. 23910

REPLY AND AMENDMENT UNDER 37 C.F.R. 1.114

Mail Stop RCE

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

This Reply and Amendment is in response to the final Office Action dated December 18, 2006, and the subsequent DECISION ON APPEAL entered by the Board of Patent Appeals and Interferences on July 20, 2009. Applicants hereby submit a Request for Continued Examination (RCE) under 37 CFR 1.114.

Please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.